Filed on behalf of Godo Kaisha IP Bridge 1

## UNITED STATES PATENT AND TRADEMARK OFFICE

\_\_\_\_\_

### BEFORE THE PATENT TRIAL AND APPEAL BOARD

\_\_\_\_\_

TAIWAN SEMICONDUCTOR MANUFACTURING COMPANY LIMITED, Petitioner,

v.

GODO KAISHA IP BRIDGE 1, Patent Owner.

\_\_\_\_\_

Case IPR2016-01246<sup>1</sup> U.S. Patent No. 6,538,324

\_\_\_\_\_

### **DECLARATION OF AMANDA DOVE**

Mail Stop PATENT BOARD, PTAB Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

<sup>&</sup>lt;sup>1</sup> Case IPR2016-01247 has been consolidated with this proceeding.



ID Rridge Evhibit 2020

- I, Amanda Dove, declare as follows:
  - 1. I am a paralegal at the law firm of Greenblum & Bernstein, P.L.C.
- 2. I provide this Declaration in connection with the above-identified *Inter Partes* Review proceedings.
- 3. Exhibit 2002 is a true copy of Schematic illustration of the Chemical Mechanical Polishing process from Steigerwald, Murarka, and Gutmann, *Chemical Mechanical Planarization of Microelectronic Materials* (1997). An exhibit label and pagination labels have been added. On March 23, 2017, https://catalog.loc.gov/ was accessed, and a copy of the Library of Congress Online Catalog Record of this book under LC Control No. 96006198 from https://lccn.loc.gov/96006198 was printed using the "Print Record" feature on this webpage. The copy of the record is now Exhibit 2034.
- 4. Exhibit 2003 is a true copy of Schematic illustration of the Chemical Mechanical Polishing process from the Motorola Company. SCSolutions.com. Accessed September 30, 2016. http://www.scsolutions.com/chemical-mechanical-planarization-cmp-controllers-0. An exhibit label and pagination labels have been added.
- 5. Exhibit 2004 is a true copy of Photograph of a Chemical Mechanical Polishing Tool from the Applied Materials Company. BusinessWire.com.

  Accessed October 5, 2016. http://www.businesswire.com/news/home/



20040711005007/en/Applied-Materials-Revolutionizes-Planarization-Technology-Breakthrough-Reflexion. An exhibit label and pagination labels have been added.

- 6. Exhibit 2005 is a true copy of Troxel, Boning, McIlrath "Semiconductor Process Representation." *Wiley Encyclopedia of Electrical and Electronics*, pp.139 –147 (1999). An exhibit label and pagination labels have been added. The paper is available online on the Wiley Online Dictionary website at http://onlinelibrary.wiley.com/doi/10.1002/047134608X.W7034/abstract.
- 7. Exhibit 2008 is a true copy of Hunt, "Low Budget Undergraduate Microelectronics Laboratory." *University Government Industry Microelectronics Symposium*, pp.81-87 (2006). An exhibit label and pagination labels have been added. The paper is available online on the IEEE *Xplore* Digital Library website at http://ieeexplore.ieee.org/document/4286358/.
- 8. Exhibit 2010 is a true copy of Burckel, "3D-ICs created using oblique processing." *Advanced in Patterning Materials and Processes XXXIII*, pp. 1–12 (2016). An exhibit label and pagination labels have been added. The paper is available online on the SPIE Digital Library at http://proceedings.spiedigitallibrary.org/proceeding.aspx?articleid=2506082.
- 9. Exhibit 2013 is a true copy of Thompson, L. F. "An Introduction to Lithography." *Introduction to Microlithography*, ACS Symposium Ser., American Chemical Society, pp. 1-13 (1983). An exhibit label and pagination labels have



been added. Relevant portions of this exhibit have been highlighted. The chapter is available online on the ACS Publications website at http://pubs.acs.org/doi/abs/10.1021/bk-1983-0219.ch001. On March 23, 2017, https://catalog.loc.gov/ was accessed, and a copy of the Library of Congress Online Catalog Record of the print version of this book under LC Control No. 83005968 from https://lccn.loc.gov/83005968 was printed using the "Print Record" feature on this webpage. The copy of the record is now Exhibit 2035.

- 10. Exhibit 2014 is a true copy of CA1275846 C to Roland et al., downloaded from the European Patent Office's Espacenet Patent Search website. An exhibit label and pagination labels have been added. Relevant portions of this exhibit have been highlighted.
- 11. Exhibit 2015 is a true and correct copy of U.S. Patent No. 5,314,843. An exhibit label and pagination labels have been added. Relevant portions of this exhibit have been highlighted.
- 12. Exhibit 2016 is a true and correct copy of U.S. Patent No. 5,231,306. An exhibit label and pagination labels have been added. Relevant portions of this exhibit have been highlighted.
- 13. Exhibit 2017 is a true and correct copy of U.S. Patent No. 4,529,621. An exhibit label and pagination labels have been added. Relevant portions of this exhibit have been highlighted.



- 14. Exhibit 2018 is a true and correct copy of U.S. Patent No. 5,310,624. An exhibit label and pagination labels have been added. Relevant portions of this exhibit have been highlighted.
- 15. Exhibit 2019 is a true and correct copy of U.S. Patent No. 5,097,422. An exhibit label and pagination labels have been added. Relevant portions of this exhibit have been highlighted.
- 16. Exhibit 2021 is a true and correct copy of U.S. Patent No. 4,952,524. An exhibit label and pagination labels have been added. Relevant portions of this exhibit have been highlighted.
- 17. Exhibit 2022 is a true copy of Bryant, A.; Haensch, W.; Geissler, S; Mandelman, Jack; Poindexter, D.; and Steger, M. "The Current-Carrying Corner Inherent to Trench Isolation." *IEEE Electron Device Letters*, Vol. 14, No. 8, pp. 412-414 (1993). An exhibit label and pagination labels have been added. Relevant portions of this exhibit have been highlighted. On March 23, 2017, https://catalog.loc.gov/ was accessed, and a copy of the Library of Congress Online Catalog Record of this journal under LC Control No. 81643614 from https://lccn.loc.gov/81643614 was printed using the "Print Record" feature on this webpage. The "Older receipts" section of the record indicates that Nos. 4-10 of Volume 14 of this journal were published in 1993. The copy of the record is now Exhibit 2036.



# DOCKET A L A R M

# Explore Litigation Insights



Docket Alarm provides insights to develop a more informed litigation strategy and the peace of mind of knowing you're on top of things.

# **Real-Time Litigation Alerts**



Keep your litigation team up-to-date with **real-time** alerts and advanced team management tools built for the enterprise, all while greatly reducing PACER spend.

Our comprehensive service means we can handle Federal, State, and Administrative courts across the country.

# **Advanced Docket Research**



With over 230 million records, Docket Alarm's cloud-native docket research platform finds what other services can't. Coverage includes Federal, State, plus PTAB, TTAB, ITC and NLRB decisions, all in one place.

Identify arguments that have been successful in the past with full text, pinpoint searching. Link to case law cited within any court document via Fastcase.

# **Analytics At Your Fingertips**



Learn what happened the last time a particular judge, opposing counsel or company faced cases similar to yours.

Advanced out-of-the-box PTAB and TTAB analytics are always at your fingertips.

#### API

Docket Alarm offers a powerful API (application programming interface) to developers that want to integrate case filings into their apps.

#### **LAW FIRMS**

Build custom dashboards for your attorneys and clients with live data direct from the court.

Automate many repetitive legal tasks like conflict checks, document management, and marketing.

#### **FINANCIAL INSTITUTIONS**

Litigation and bankruptcy checks for companies and debtors.

## **E-DISCOVERY AND LEGAL VENDORS**

Sync your system to PACER to automate legal marketing.

